

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Yasuhiro OMURA) Present Group Art Unit: 2851
)
Application No.: 1.53(b) Continuation of) Present Examiner: Hung Nguyen
Application No. 09/865,734)
)
Filed: Herewith)
)
For: PROJECTION OPTICAL SYSTEM,)
EXPOSURE APPARATUS)
INCORPORATING THIS)
PROJECTION OPTICAL SYSTEM,)
AND MANUFACTURING METHOD)
FOR MICRO DEVICES USING)
THE EXPOSURE APPARATUS)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

PRELIMINARY AMENDMENT

Prior to the examination of the above application, please amend this application
as follows:

Amendments to the Specification are included in this paper beginning on page
2.

Amendments to the Claims are reflected in the listing of claims in this paper
beginning on page 3.

Remarks/Arguments follow the amendment sections of this paper beginning on
page 14.

FINNEGAN
HENDERSON
FARABOW
GARRETT &
DUNNER LLP

1300 I Street, NW
Washington, DC 20005
202.408.4000
Fax 202.408.4400
www.finnegan.com